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PATENT September 15, 2000

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Sir:

Transmitted herewith for filing is the patent application of

Inventor(s):

Xiuling Li, Paul W. Bohn, Jonathan V. Sweedler

For:

METAL-ASSISTED CHEMICAL ETCH POROUS

R FOR PATENTS

SILICON FORMATION METHOD

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	a)	Basic Fee									\$ 690.00
	b)	Independent Claims	_3_	<u>-3</u>	=	_ <u>0</u> _x		\$ 7	78.00	=	\$
	c)	Total Claims	21	- 20_	_ =	_1	X	\$:	18.00	=	\$ <u>18.00</u>
	d)	Fee for Multiple Claims						\$20	60.00	=	\$
	Total Filing Fee								\$_708.00		
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